

1/19

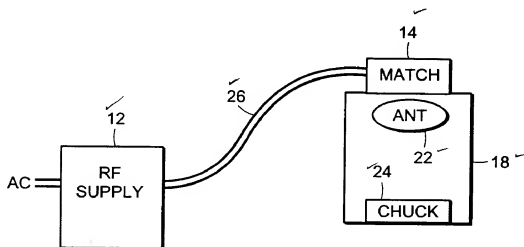


FIG. 1A  
PRIOR ART

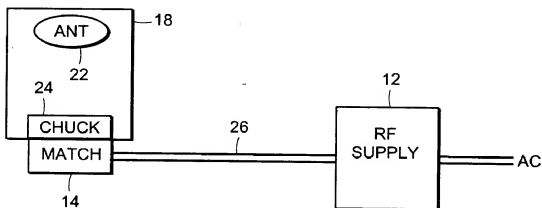


FIG. 1B  
PRIOR ART

2/19

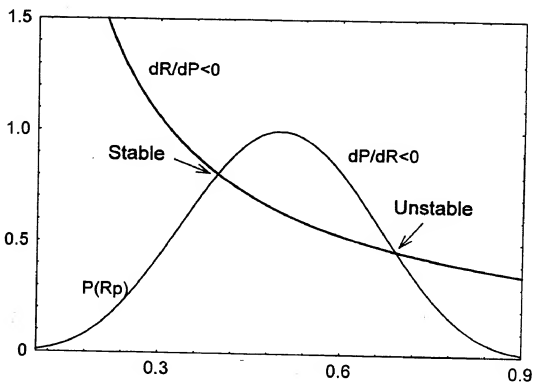


FIG. 2

3/19

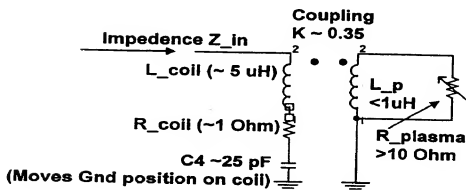


FIG. 3A

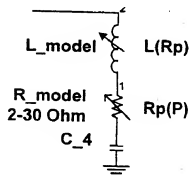


FIG. 3B

4/19

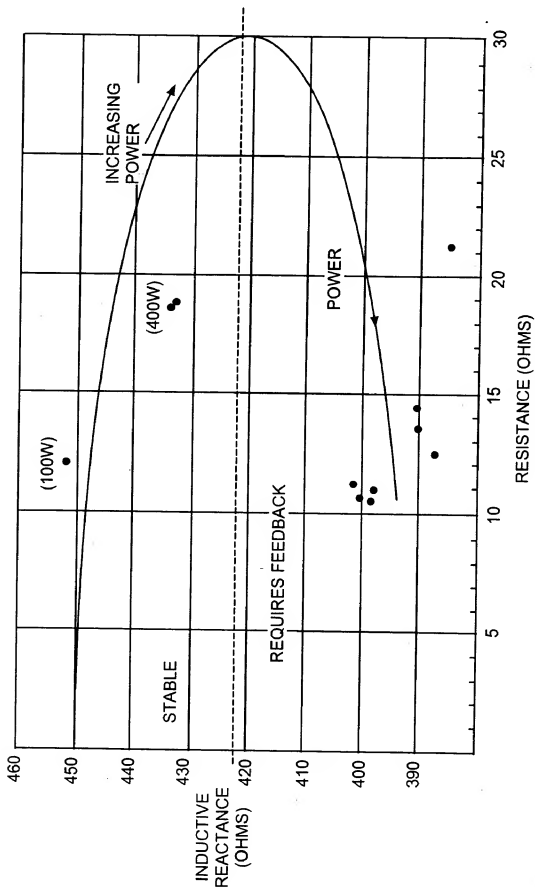


FIG. 4

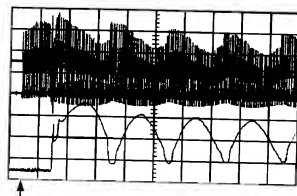


FIG. 5

[illegible]

6/19

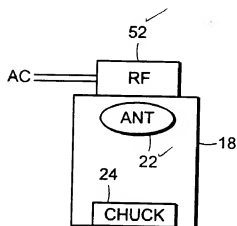


FIG. 6A

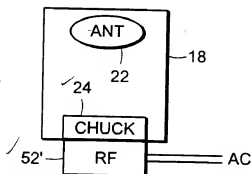


FIG. 6B

7/19

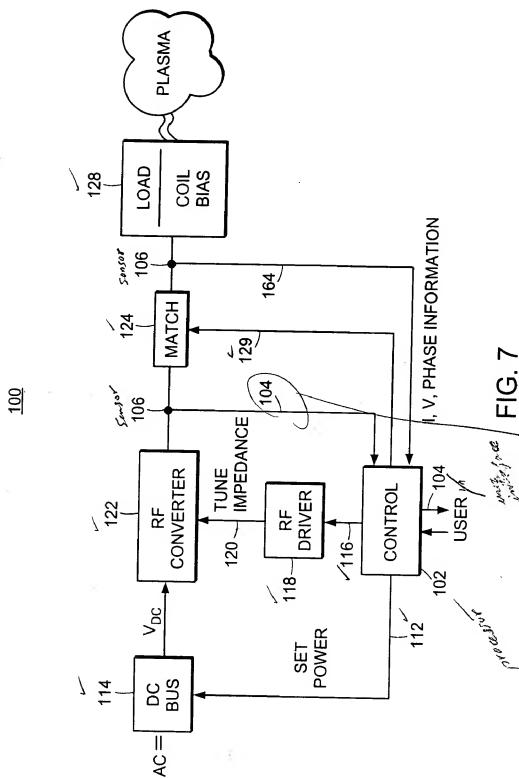


FIG. 7

150

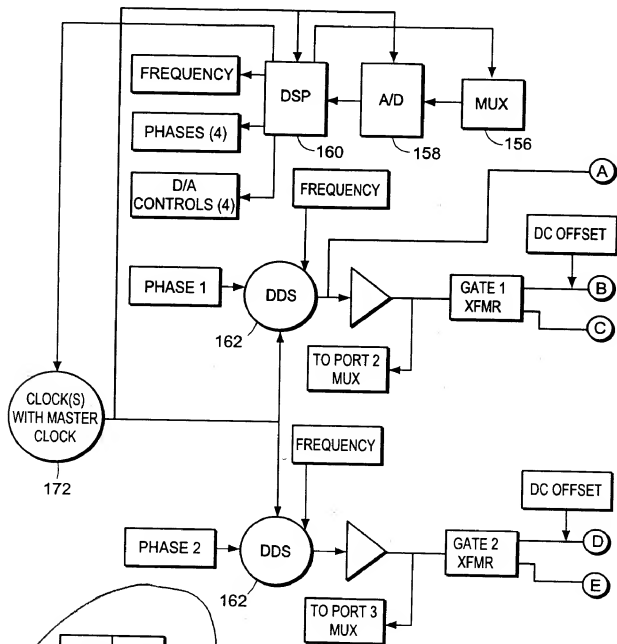


FIG. 8

FIG. 8A

FIG. 8A

*H-bridge control circuit*

9/19

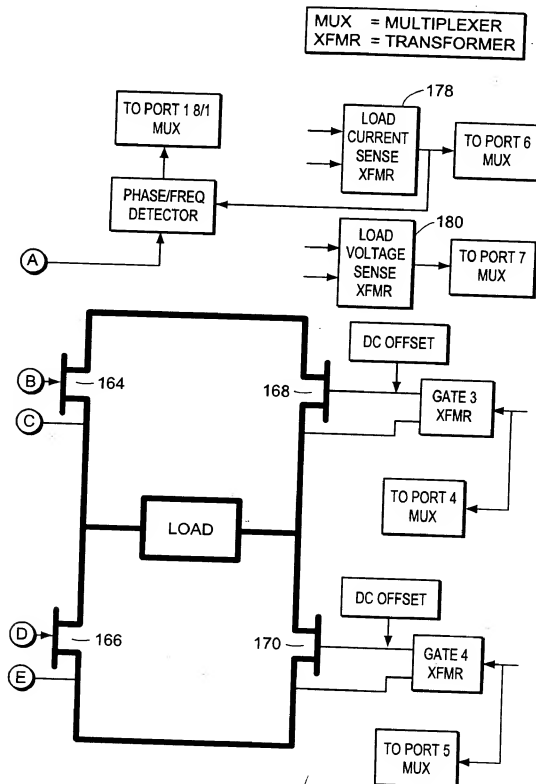
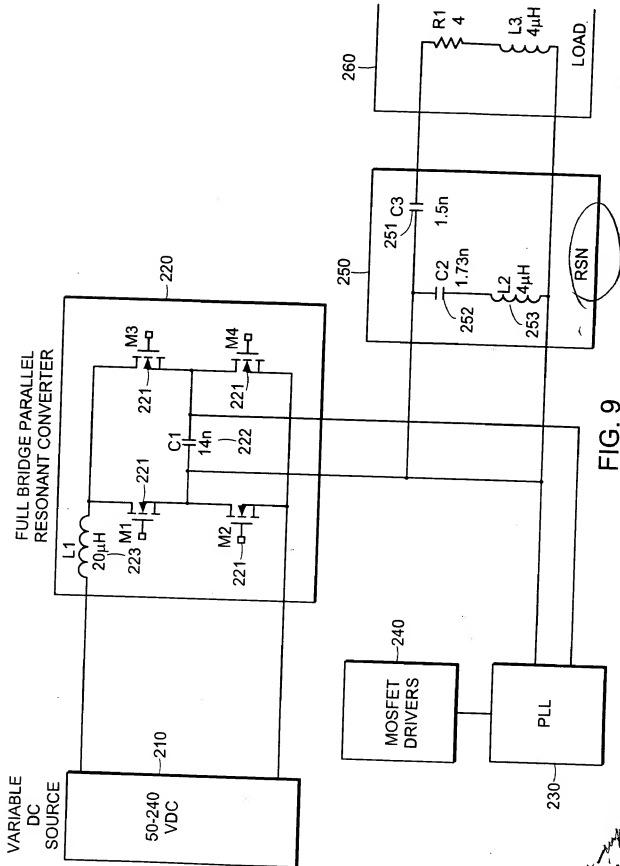


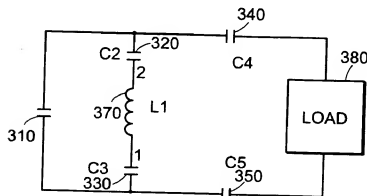
FIG. 8B

10/19



*power supply system  
including  
resonance stabilization  
networks*

11/19



*resistance  
substitution  
network*

FIG. 10

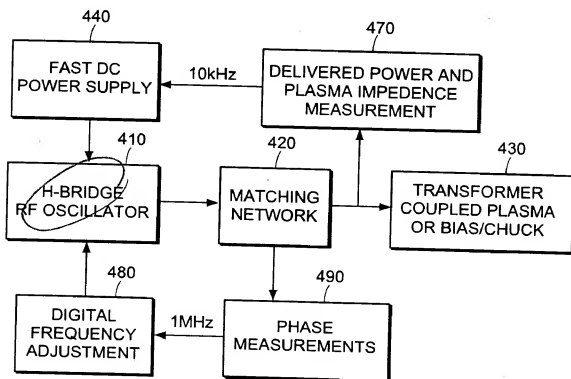


FIG. 11

*RF plasma generator  
includes:  
DC power supply  
coupled with two loops*

12/19

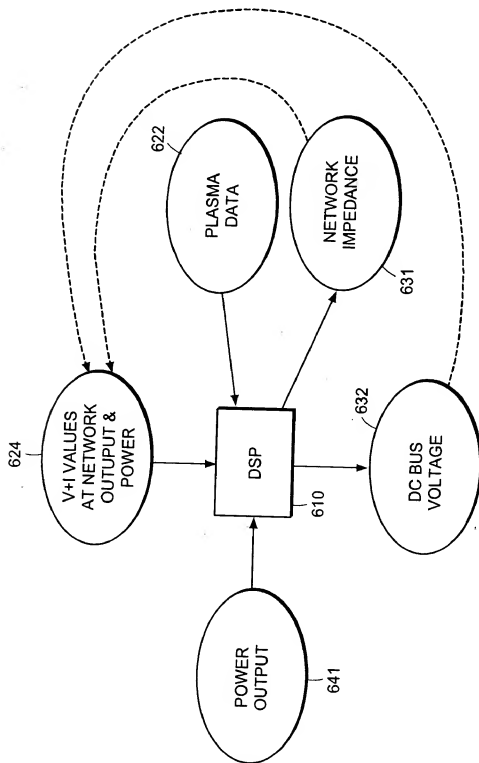


FIG. 12

13/19

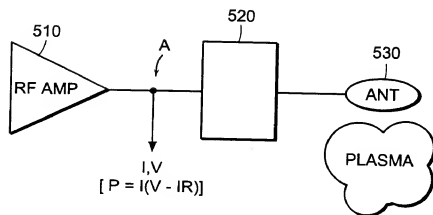
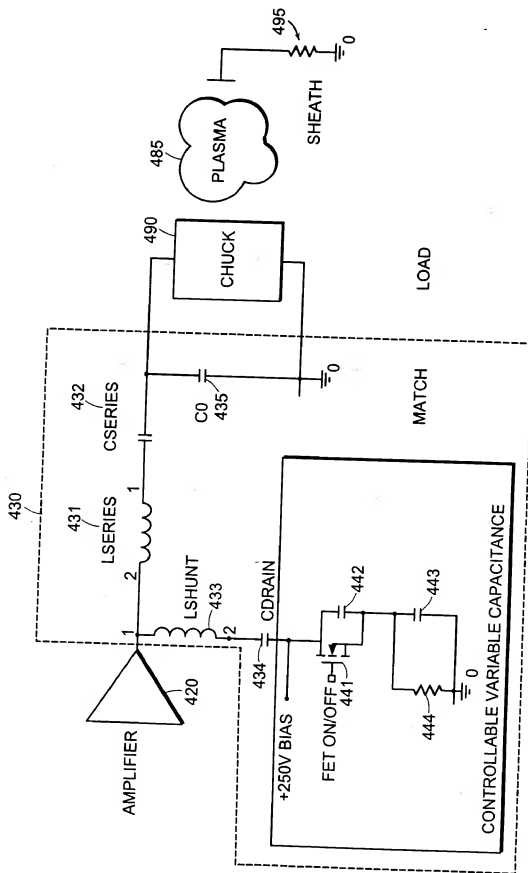


FIG. 13A

14/19



15/19

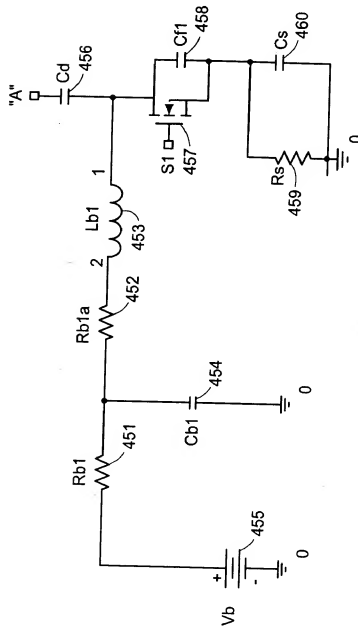


FIG. 14

*smooth switching  
matching network*

16/19

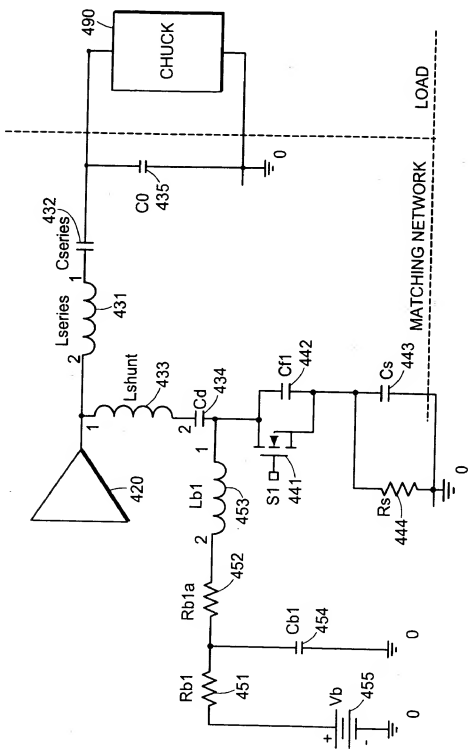


FIG. 15

*plasma processing system  
including  
matching network*

17/19

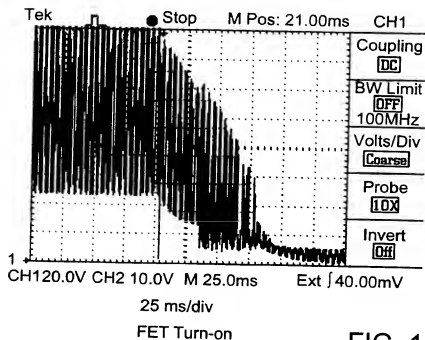


FIG. 16A

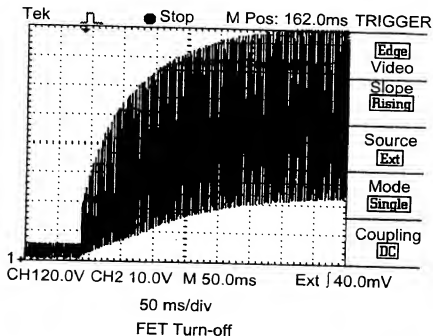


FIG. 16B

18/19

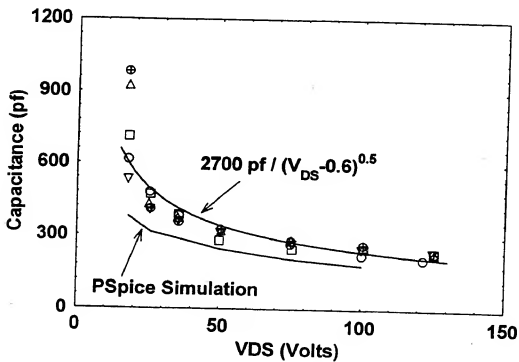


FIG. 17

19/19

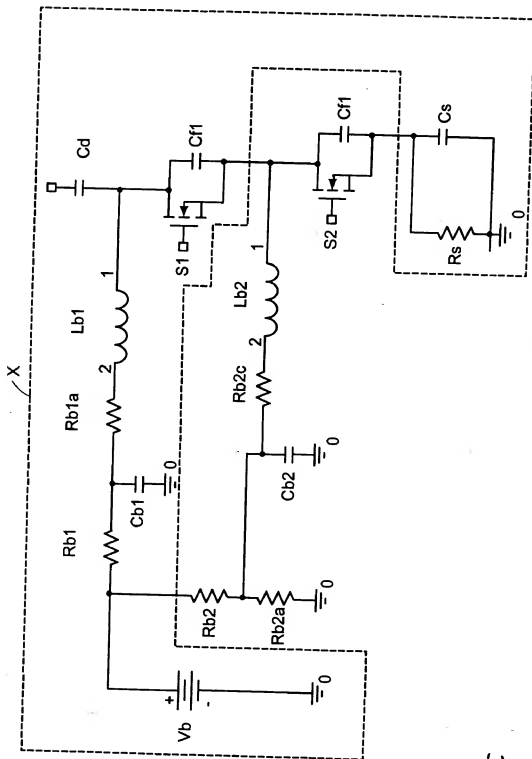


FIG. 18

including  
multiple  
smooth output sections

19/19

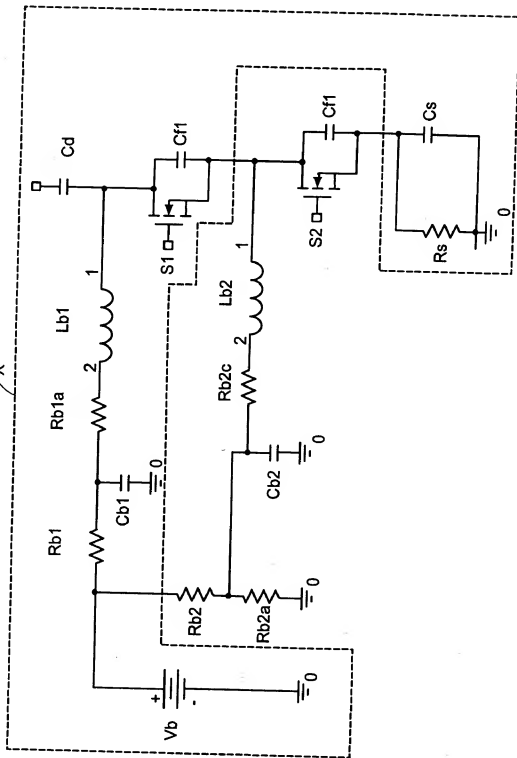


FIG. 18